

# Photo-CVD approach to high- $\kappa$ dielectric deposition

EU "TOPS" consortium invites you to a  
*workshop*  
on the deposition of high- $\kappa$  thin films  
by  
ultra-violet injection liquid source CVD

## UVILS CVD

**Venue:** Palais des Congrès  
(Congress Centre)  
Strasbourg, France:

**Date/Time:** June 8<sup>th</sup>; 10 am to 4 pm  
(Final day of EMRS)

Free Registration (limited numbers)  
Room details (EMRS notice board)

**Contact:** Paul Hurley  
**Email:** phurley@nmrc.ie  
**Tel:** 00353 21 4904080



Furnaces and thin film deposition

**INORGETECH**



## Outline

**10am - 12.30pm:**

### **Project Motivation and Overview**

- UVILS-CVD Technique
- Precursors
- Liquid injection source
- UV assisted deposition technique

**12.30pm - 1.30pm: Lunch**

**1.30pm - 2.30pm:**

### **Example high- $\kappa$ materials**

- Ta<sub>2</sub>O<sub>5</sub> and TiO<sub>2</sub>
- physical characterisation
- electrical characterisation

**2.30pm - 4.00pm:**

### **Open Discussion**

- suitability of UVILS CVD
  - to high- $\kappa$  on silicon
- high- $\kappa$  options



Furnaces and thin film deposition

**INORGETECH**

